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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/713,362	11/14/2003	Eric Dickey	6333-67325	9159
	7590 06/14/2007 SPARKMAN, LLP	EXAMINER		
One World Trade Center Suite 1600 121 S. W. Salmon Street			KACKAR, RAM N	
			ART UNIT	PAPER NUMBER
Portland, OR 97			1763	
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			06/14/2007	PAPER

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

	Application No.	Applicant(s)				
	10/713,362	DICKEY ET AL.				
Office Action Summary	Examiner	Art Unit				
	Ram N. Kackar	1763				
The MAILING DATE of this communication app Period for Reply	The MAILING DATE of this communication appears on the cover sheet with the correspondence address					
A SHORTENED STATUTORY PERIOD FOR REPLY WHICHEVER IS LONGER, FROM THE MAILING DA - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication. - If NO period for reply is specified above, the maximum statutory period value for the provided period for reply within the set or extended period for reply will, by statute the provided period by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION 36(a). In no event, however, may a reply be tim will apply and will expire SIX (6) MONTHS from , cause the application to become ABANDONEI	l. ely filed the mailing date of this communication. O (35 U.S.C. § 133).				
Status						
 Responsive to communication(s) filed on <u>09 A</u> This action is FINAL. 2b) This Since this application is in condition for alloware closed in accordance with the practice under E 	action is non-final. nce except for formal matters, pro					
Disposition of Claims	·					
4) ☐ Claim(s) 1-13 and 20 is/are pending in the app 4a) Of the above claim(s) is/are withdray 5) ☐ Claim(s) is/are allowed. 6) ☐ Claim(s) 1-13 and 20 is/are rejected. 7) ☐ Claim(s) is/are objected to. 8) ☐ Claim(s) are subject to restriction and/or	wn from consideration.					
Application Papers						
9) The specification is objected to by the Examine 10) The drawing(s) filed on is/are: a) accomposed and accomposed applicant may not request that any objection to the Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the Examine	epted or b) objected to by the Edrawing(s) be held in abeyance. See ion is required if the drawing(s) is obj	37 CFR 1.85(a). ected to. See 37 CFR 1.121(d).				
Priority under 35 U.S.C. § 119						
 12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some * c) None of: 1. Certified copies of the priority documents have been received. 2. Certified copies of the priority documents have been received in Application No. 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received. 						
Attachment(s) 1) Notice of References Cited (PTO-892)	4) 🔲 Interview Summary (PTO-413)				
 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO/SB/08) Paper No(s)/Mail Date 11/14/03 & 1/26/04. 	Paper No(s)/Mail Da 5) Notice of Informal Pa 6) Other:	te				

DETAILED ACTION

Election/Restrictions

1. Applicant's election without traverse of claims 1-13 and 20 and cancellation of claims 14-19 in the reply filed on 4/9/2007 is acknowledged.

Claim Rejections - 35 USC § 112

2. The following is a quotation of the first paragraph of 35 U.S.C. 112:

The specification shall contain a written description of the invention, and of the manner and process of making and using it, in such full, clear, concise, and exact terms as to enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to make and use the same and shall set forth the best mode contemplated by the inventor of carrying out his invention.

3. Claim 5 is rejected under 35 U.S.C. 112, first paragraph, as failing to comply with the enablement requirement. The claim(s) contains subject matter which was not described in the specification in such a way as to enable one skilled in the art to which it pertains, or with which it is most nearly connected, to make and/or use the invention. The recitation of a flow shield in this claim is not disclosed in the specification.

Claim Rejections - 35 USC § 102

4. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 5. Claims 1 and 4-10 are rejected under 35 U.S.C. 102(b) as being anticipated by Eres et al (US 5330610).

Application/Control Number: 10/713,362

Page 3

Art Unit: 1763

Eres et al disclose an ALE (atomic layer epitaxy apparatus) (abstract and Fig 1) where precursors are delivered in pulses where there may be one or more than one precursors (Col 8 lines 56-61). Eres et al further disclose an optical monitor to detect optical spectrum and a controller to control in closed loop deposited parameters of the deposited film (Col 2 lines 21-23, Col 3 lines 3-34, Col 4 lines 41-54 and Col 10 lines 26-46).

6. Claims 1 and 4-10 are rejected under 35 U.S.C. 102(b) as being anticipated by Bachmann et al (US 5552327).

Bachmann et al disclose an ALE (atomic layer epitaxy apparatus) (abstract and Fig 1) where two precursors are delivered in pulses. Bachmann et al further disclose an optical monitor to detect optical spectrum and a controller to control in closed loop deposited parameters of the deposited film (Col 2 lines 21-23, Col 3 lines 3-38, Col 6 lines 14-26, Col 7 lines 39-52 and Col 10 lines 17-28).

Claim Rejections - 35 USC § 103

- 7. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 8. Claims 2-3, 13 are rejected under 35 U.S.C. 103(a) as being unpatentable over Eres et al (US 5330610) in view of Muller et al (US 5724144) and further in view of Toshiaki Sango (JP 09209179) or Koji Eriguchi (US 5985032).

Application/Control Number: 10/713,362

Art Unit: 1763

Eres et al disclose the holding of substrate in a conventional way. However it is known that windows used for optical monitoring get unneeded deposition to cause errors in monitoring.

Muller et al teach that by monitoring substrates from the rear does not need any monitoring window (abstract and Fig 4). Miller et al disclose this by using holes drilled in substrate holders covered by a window behind the substrate. Muller et al do not disclose the substrate back extensively open for monitoring.

Toshiaki Sango discloses monitoring a transparent substrate mounted on processing chamber with seal and allows monitoring of film deposited from inside to be monitored from outside (Abstract and Fig1-Fig 3).

Koji Eriguchi discloses a similar window (Fig 10a and 11).

Therefore it would have been obvious for one of ordinary skill in the art at the time of invention to install substrate so that deposition may take place inside while monitoring could be done from outside so as to obviate the need of optical windows which become clouded due to unnecessary deposition.

9. Claims 11 and 12 are rejected under 35 U.S.C. 103(a) as being unpatentable over Eres et al (US 5330610) in view of Tsai (US 5858102).

Eres et al do not disclose planetary rotation of substrate holder. Tsai teaches that planetary motion of substrate holder increases uniformity of deposition (Abstract).

Therefore it would have been obvious for one of ordinary skill in the art at the time of invention to have planetary rotation of the substrate holder for uniformity of deposition.

Application/Control Number: 10/713,362 Page 5

Art Unit: 1763

10. Claim 20 is rejected under 35 U.S.C. 103(a) as being unpatentable over Eres et al (US 5330610) in view of Byun et al (US 6620723).

Eres et al disclose an ALE (atomic layer epitaxy apparatus) (abstract and Fig 1) where precursors are delivered in pulses where there may be one or more than one precursors (Col 8 lines 56-61). Eres et al further disclose an optical monitor to detect optical spectrum and a controller to control in closed loop deposited parameters of the deposited film (Col 2 lines 21-23, Col 3 lines 3-34, Col 4 lines 41-54 and Col 10 lines 26-46).

Eres et al does not explicitly disclose the controller to be a computer with a readable medium with instruction for deposition.

Byun et al disclose using a computer with a readable medium with instruction for ALE deposition (Col 3 lines 27-52).

Therefore it would have been obvious for one of ordinary skill in the art at the time of invention to have a computer with a readable medium with instruction for deposition for automation related advantages of through put, accuracy and repeatability.

11. Claims 1, 4-10 and 20 are rejected under 35 U.S.C. 103(a) as being unpatentable over Eres et al (US 5164040) in view of Byun et al (US 6620723).

Eres et al disclose an ALE (atomic layer epitaxy apparatus) (abstract and Fig 1) where two precursors are delivered in pulses (abstract and Fig 1). Eres et al further disclose an optical monitor to detect optical spectrum.

Art Unit: 1763

Eres et al does not explicitly disclose the controller to be a computer with a readable medium with instruction for deposition in order to control in closed loop deposited parameters of the deposited film.

Byun et al disclose using a computer with a readable medium with instruction for ALE deposition (Col 3 lines 27-52) and a closed loop control of deposition.

Therefore it would have been obvious for one of ordinary skill in the art at the time of invention to have a computer with a readable medium with instruction for deposition for automation related advantages of through put, accuracy and repeatability.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Ram N. Kackar whose telephone number is 571 272 1436. The examiner can normally be reached on M-F 8:00 A.M to 5:P.M.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Parviz Hassanzadeh can be reached on 571 272 1435. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Application/Control Number: 10/713,362

Art Unit: 1763

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

Page 7

Ram Kackar Primary Examiner AU 1763